



# A fresh approach to surface metrology for additive manufacture

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## A paradigm shift in surface metrology







### Measurement technologies



## Direct feature comparison

SEM

#### Optical microscopy

The University of **Nottingham** 

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#### X-ray computed tomography







## Direct feature comparison

SEM

#### Optical microscopy

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#### Coherence scanning interferometry



Focus variation









#### X-ray computed tomography





### Extracted profiles

An example from focus variation (alignment by eye & software auto-registration)



# Direct topographical comparison

The University of Nottingham





Direct topographical comparison

### **Our current work**

Extending our method of surface assessment by comparison of topographies (previously **qualitative**) to a **statistically robust**, **quantitative** approach.







## The elephant in the room: what about when we can't reach the surface?

# Surfaces of objects with complex form



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# Surfaces of objects with complex form





### **XCT** Pipeline



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### The lost information





## The big problem: surface determination



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### An example from elsewhere: microholes



Rabani, Senin, Hemli, Butler-Smith & Leach, 2016, euspen's 16th International Conference & Exhibition, (Nottingham, UK)

## Internal surfaces: a test case



### **Selective laser melting of metals**

- Hollow Ti6Al4V cube of (10 × 10 × 10) mm from an EOSINT M 280, separable to allow measurement of internal surfaces
- Top surface: comparable to previous work and representative of SLM surfaces
- Sides of recessed section used for relocation



# So how does XCT compare?

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### Qualitative similarity, and many parameters in a similar ballpark...



Shown: unfiltered raw data, while parameters were calculated for scale-limited surfaces using following cutoffs: S-filter of 11 μm based on grid of 4 × 4 pixels in lowest resolution data, L-filter of 0.5 mm to separate roughness and waviness based on visual assessment of surfaces.

### Current work



Development of a **rigorous statistical model** for direct comparison of topographies

Investigation into the specific requirements of using **XCT** for investigation of **surface texture** to develop a **good practice model**, in terms of measurement setup, reconstruction and analysis

Participation in the **CT-STARR** (CT-Surface Texture for Additive Round Robin) coordinated by the University of Huddersfield

Investigation into the specific requirements of using **optical instruments** for measurement of **complex AM surfaces** to develop a **good practice model** in terms of measurement setup and analysis

Development of new technology for in-line, layer-by-layer surface measurement





## A fresh approach to surface metrology for additive manufacture *Thanks for your attention*

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